■ UCLouvain lelec2895 Design of micro and na

2019

Design of micro and nanosystems

In view of the health context linked to the spread of the coronavirus, the methods of organisation and evaluation of the learning units could be adapted in different situations; these possible new methods have been - or will be - communicated by the teachers to the students.

5 credits	30.0 h + 30.0 h	Q1

Teacher(s)	Francis Laurent ;				
Language :	English				
Place of the course	Louvain-la-Neuve				
Main themes	This cursus is part of the MEMS & NEMS, Micro and Nanotechnology ELEC options. LELEC2895 is focused on the understanding and the design of micro-electromechanical devices (MEMS), on transducers (sensors, actuators) made using micro and nanofabrication technologies, to their co-integration with integrated circuits (IC), to their multiphysics simulation and characterisation, to their reliability and their interconnect.				
Aims	 With respect to the AA referring system defined for the Master in Electrical Engineering, the course contributes to the develoopment, mastery and assessment of the following skills : •AA1.1, AA1.2, AA1.3 •AA2.1, AA2.2, AA2.3, AA2.4, AA2.5 •AA3.1, AA3.2, AA3.3 •AA4.2, AA4.3, AA4.4 •AA5.1, AA5.2, AA5.3, AA5.4, AA5.5, AA5.6 				
	• AA6.1, AA6.3, AA6.4 1				
	After this course, the student will be able to:				
	 Describe the transduction principles and scaling effects Understand specifications for a MEMS Design MEMS and NEMS and use multiphysics simulation softwares and tools Identify electronic circuits adapted to MEMS and NEMS Identify fabrication techniques required to make such devices Analyse the reliability of miniaturised devices Present (report) and defend (slides) the results of a group project (with 2 to 4 students) 				
Evaluation methods	Due to the COVID-19 crisis, the information in this section is particularly likely to change. The course is subject to continuous evaluation for 2/3 of the final grade during the semester when submitting group work reports on the practical work sessions, and for 1/3 by an individual oral examination in session. The in-session exam is a closed book exam but is assisted by the course form. The distribution of marks may be waived in the event of a noticeable difference in performance between the written work and the final oral performance, in which case only the latter's mark will be considered.				
Teaching methods	 Due to the COVID-19 crisis, the information in this section is particularly likely to change. The course is organised as following 10 sessions of theoretical lectures, based on flipped classes helped by the resolution in students group of numerous examples and cases 1 tutorial session related to the software tools 3 sessions of design practical works, with teaching support 1 industrial seminar 				
Content	 MEMS design methodology Scale effects and transduction principles Sensors and actuators: electrical, mechanical, thermal, optical, (bio)chemical, etc Fabrication processes Selection of electronic interface circuits Multiphysics simulations 				

Université catholique de Louvain - Design of micro and nanosystems - en-cours-2019-lelec2895

Inline resources	Moodle http://moodleucl.uclouvain.be/course/view.php?id=7527
Bibliography	 Supports Transparents disponibles sur Moodle/Slides available on Moodle Livre de référence disponible à la Bibliothèque des Sciences et Technologies/Reference book available at the Science and Technology Library (Ville Kaajakari, "Practical MEMS", Small Gear Publishing)
Other infos	LELEC2560 Micro and Nanofabrication Techniques is a desirable prerequisite. Basic knowledge of electronics, solid-state physics, materials science and chemistry is an advantage.
Faculty or entity in charge	ELEC

Programmes containing this learning unit (UE)						
Program title	Acronym	Credits	Prerequisite	Aims		
Master [120] in Physical Engineering	FYAP2M	5		٩		
Master [120] in Electrical Engineering	ELEC2M	5		٩		
Master [120] in Chemical and Materials Engineering	KIMA2M	5		٩		